

19. (Twice Amended) An apparatus for depositing a material having a work function of approximately 1 eV on a substrate by laser ablation using short-wavelength photons, including:

a deposition chamber,

a target containing a material having a work function of approximately 1 eV in said chamber,

a laser capable of directing photons at or below visible wavelength into said chamber and onto said target,

means for rotating said target,

means for controlling the composition of the deposit by controlling at least one of the groups consisting of the environment of said deposition chamber, the target composition, and the target temperature.

a substrate located in said chamber,

means for holding said substrate, and

means for at least rotating said substrate.

C2
26. (Amended) The apparatus of Claim 19, wherein said target is composed of barium metal oxide or an alkali metal oxide.

C3
28. (Amended) The apparatus of Claim 19, wherein said means for holding said substrate is rotated at 1 to 10 rpm and tilted at an angle in a range of 0 to 90° with respect to horizontal.